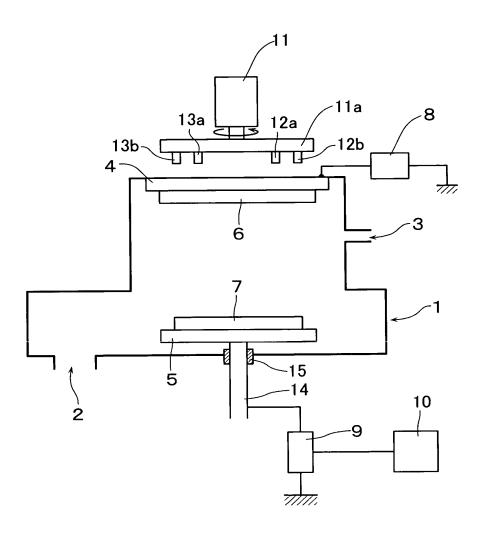
Title: BIAS SPUTTERING FILM FORMING PROCESS AND BIAS SPUTTERING FILM FORMING APPARATUS Inventor: Myounggoo LEE et al. Docket Number: 101136-00095

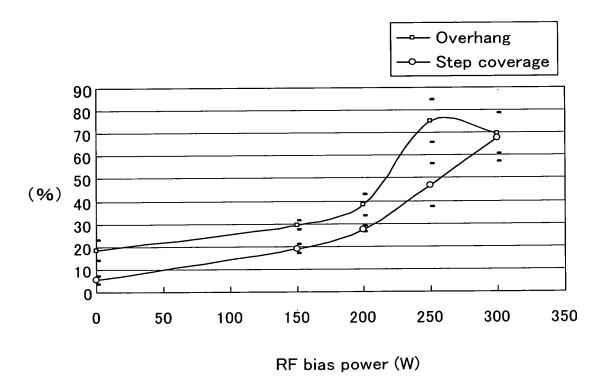
FIG.1



FORMING APPARATUS Inventor: Myounggoo LEE et al. Docket Number: 101136-00095

FIG.2A FIG.2B FIG.2C

FIG.3

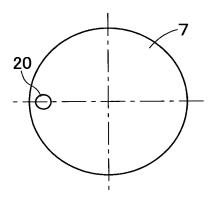


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FIG.4A

FIG.4B



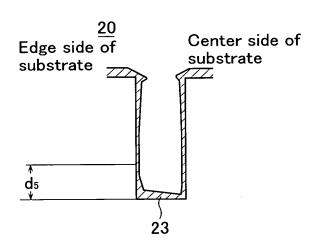


FIG.4C

Height location at minimum side coverage (ds/nm)

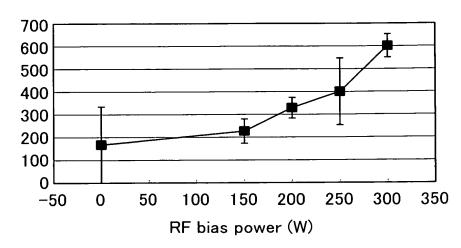


FIG.5A

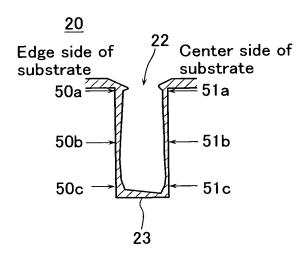
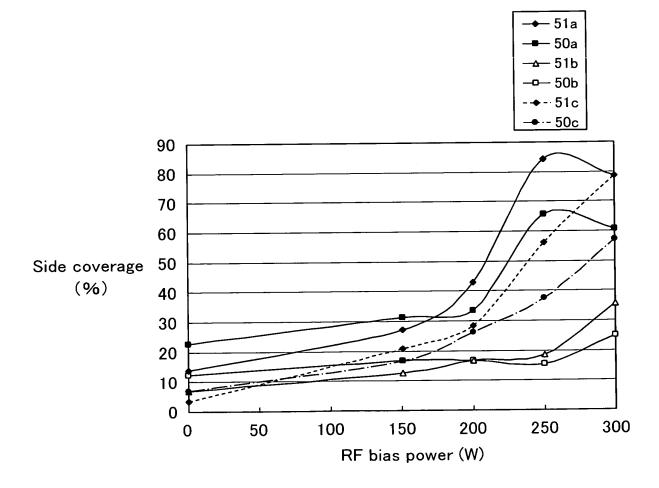


FIG.5B



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FIG.6A

20(Hole located in edge of substrate)

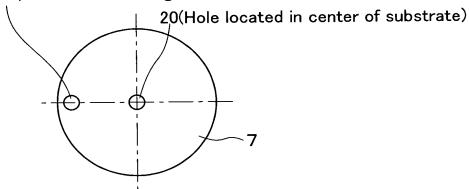
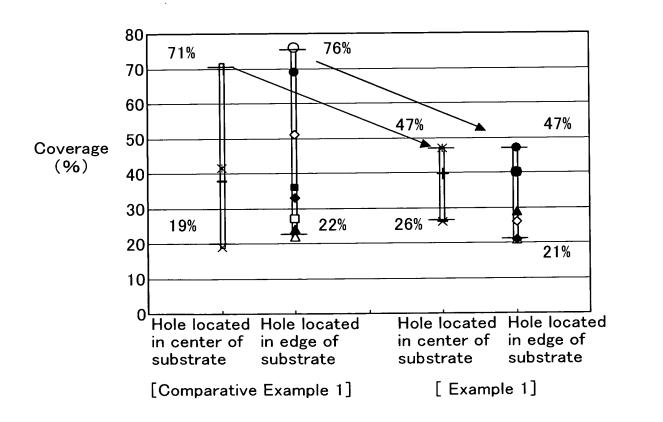


FIG.6B



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FIG.7

